M-15281US 10/753,673

## IN THE CLAIMS

The following is a complete listing of the pending claims:

1. (currently amended) A two-transistor PMOS memory cell, comprising:

a PMOS select transistor having a drain and a source formed as separate P+ diffusion regions in an N- well;

a PMOS floating gate transistor having a drain and a source formed as separate P+ diffusion regions in the N-well, wherein the P+ diffusion region that forms the floating gate transistor's drain is the same P+ diffusion region that forms the select gate transistor's source; and

an N implant underlying only the P+ diffusion region that forms the floating gate transistor's drain such that an N implant does not underlie either of the P+ diffusion regions forming the select gate' transistor drain and the floating gate's transistor's source, and wherein a lateral extent of the N implant is no greater than a lateral extent of the P+ diffusion region that forms the floating gate transistor's drain.

- (cancelled)
- 3. (original) The two-transistor PMOS memory cell of claim 2, wherein the drain of the PMOS select transistor couples to a bit line of a memory array, and wherein a select gate of the PMOS select transistor couples to a word line of the memory array.

4. (original) The two-transistor PMOS memory cell of claim 2, wherein a floating gate

4. (original) The two-transistor PMOS memory cell of claim 2, wherein a floating gat of the PMOS floating gate transistor is formed in a first polysilicon layer, and wherein a

Serial No. 10/753,673

M-15281US 10/753,673

control gate of the PMOS floating gate transistor is formed in a second polysilicon layer.

- 5. (original) The two-transistor PMOS memory cell of claim 2, wherein the memory cell includes a single polysilicon layer containing a floating gate of the PMOS floating gate transistor, and wherein a control gate of the PMOS floating gate transistor is formed as a P+ diffusion region in the N- well.
- 6. (original) The two-transistor PMOS memory cell of claim 2, wherein the memory cell is configured such that the floating gate transistor may be programmed using band-to-band tunneling.
- 7. (original) The two-transistor PMOS memory cell of claim 2, wherein the memory cell is configured such that the floating gate transistor may be programmed using Fowler Nordheim tunneling.
- 8. (original) The two-transistor PMOS memory cell of claim 2, wherein the P+ diffusion region that forms the floating gate transistor's drain has a thickness of approximately 0.1 to 0.25 microns.
- 9. (original) The two-transistor PMOS memory cell of claim 2, wherein the thickness of the N implant underlying the P+ diffusion region that forms the floating gate transistor's drain is approximately 0.1 to 0.25 microns.
  - 10. (withdrawn)

LAW OFFICES OF MACHIERSON KWON CHEN A REID LLP

2402 Micholson Drive SUITS 210 Irvine. CA 92613 (349) 752-7640

Serial No. 10/753,673

M-15281US 10/753,673

- 11. (withdrawn)
- 12. (withdrawn)
- 13. (withdrawn)
- 14. (withdrawn)

LAW OPFICES OF MACPHERSON KWOK CHEN & HEID LLP

2402 bitchelson Drivo SUITS 210 Invine CA 92612 (949) 752-7040 FAX (949) 753-7049

Serial No. 10/753,673